

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Application Number:	10/767,046
Filing Date:	March 11, 2004
First Named Inventor:	Jung-hyun Lee et al.
Examiner Name:	SARA W CRANE
Attorney Docket No.:	1030681-000634

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NON-PATENT LITERATURE DOCUMENTS

Examiner initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	Sneh, Ofer et al., <i>Thin film atomic layer deposition equipment for semiconductor processing</i> , Thin Solid Films 402 (2002) 248-261
	Copy of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929
	English Translation of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929

Examiner Signature		Date Considered	
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